



INFORMATION CITED BY APPLICANT THAT MAY BE MATERIAL TO THE
PROSECUTION OF THE SUBJECT APPLICATION

Applicant: L. Chen Attorney Docket No.: SEMT116013
Application No.: 09/045,245 Group Art Unit: 1741
Filed: March 20, 1998 Examiner: W. Nicholas
Title: METHOD FOR ELECTROLYTICALLY DEPOSITING COPPER ON A
SEMICONDUCTOR WORKPIECE
Batch No.: S37 Notice of Allowability Date: 09/19/00

U.S. PATENT DOCUMENTS

*Examiner Initial	ID	Document No.	Date	Name
U1.	U1	3,878,066	04/1975	Dettke et al.
U2.	U2	4,576,689	03/1986	Makkaev et al.

FOREIGN PATENT DOCUMENTS

*Examiner Initial	ID	Document No.	Date	Country	Translation Provided	
					Yes	No
None						

OTHER INFORMATION

(Including Author, Title, Date, Pertinent Pages, Etc.)

*Examiner Initial	ID
None	

Examiner

Woj [Signature]

Date Considered

1/8/01

*Examiner: Initial if reference considered, whether or not citation is in conformance with M.P.E.P. § 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.